

L Number	Hits	Search Text	DB	Time stamp
1	507	250/\$.ccls. and ((scanning electron microscope) SEM) and auger	USPAT; EPO; JPO; DERWENT	2004/08/05 07:59
2	224	(250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and deflect\$5	USPAT; EPO; JPO; DERWENT	2004/08/05 07:45
3	76	((250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and deflect\$5) and objective adj lens	USPAT; EPO; JPO; DERWENT	2004/08/05 07:45
4	92	(250/\$.ccls. and ((scanning electron microscope) SEM) and auger) and objective adj lens	USPAT; EPO; JPO; DERWENT	2004/08/05 08:00
-	1404	250/\$.ccls. and electron adj beam and optical adj system	USPAT; EPO; JPO; DERWENT	2003/04/22 12:55
-	142	(250/\$.ccls. and electron adj beam and optical adj system) and lens and shield	USPAT; EPO; JPO; DERWENT	2003/04/23 07:57
-	9	((250/\$.ccls. and electron adj beam and optical adj system) and lens and shield) and auger	USPAT; EPO; JPO; DERWENT	2002/12/12 09:58
-	3369	250/310-311.ccls.	USPAT; EPO; JPO; DERWENT	2002/12/13 07:38
-	120	250/310-311.ccls. and electron adj beam and lens and shield	USPAT; EPO; JPO; DERWENT	2002/12/12 10:34
-	107	(250/310-311.ccls. and electron adj beam and lens and shield) and microscope	USPAT; EPO; JPO; DERWENT	2002/12/13 07:38
-	27	secondary adj electron and backscatter and detector and SEM	USPAT; EPO; JPO; DERWENT	2002/12/12 12:42
-	404	250/310-311.ccls. and SEM	USPAT; EPO; JPO; DERWENT	2002/12/12 12:57
-	289	(250/310-311.ccls. and SEM) and secondary adj electron	USPAT; EPO; JPO; DERWENT	2002/12/13 09:50
-	9	("4789787" "4894549" "5182453" "5422486" "5436460" "5444243" "5510617" "6246058" "6259094").PN.	USPAT	2002/12/12 14:51
-	10	(250/310-311.ccls. and electron adj beam and lens and shield) and microscope and capacitor	USPAT; EPO; JPO; DERWENT	2002/12/13 07:38
-	20	(250/310-311.ccls. and SEM) and secondary adj electron and magnetic adj pole	USPAT; EPO; JPO; DERWENT	2002/12/13 12:31
-	5	(250/310-311.ccls. and SEM) and auger and deflection adj plate	USPAT; EPO; JPO; DERWENT	2002/12/13 12:34
-	0	(250/310-311.ccls. and SEM) and virtual adj auger	USPAT; EPO; JPO; DERWENT	2002/12/13 12:32
-	39	(250/310-311.ccls. and SEM) and auger	USPAT; EPO; JPO; DERWENT	2002/12/13 13:27
-	3	("4126781").PN.	USPAT; EPO; JPO; DERWENT	2002/12/13 13:27
-	0	250/\$.ccls. and electron adj beam and optical adj system and dual adj pole adj magnetic adj lens	USPAT; EPO; JPO; DERWENT	2002/12/13 14:21

-	70	250/\$.ccls. and electron adj beam and optical adj system and magnetic adj pole	USPAT; EPO; JPO; DERWENT	2002/12/13 15:42
-	4	250/\$.ccls. and electron adj beam and optical adj system and spherical adj capacitor	USPAT; EPO; JPO; DERWENT	2002/12/13 14:56
-	1	250/\$.ccls. and electron adj beam and optical adj system and electrostatic adj capacitor	USPAT; EPO; JPO; DERWENT	2002/12/13 14:57
-	2	250/\$.ccls. and electron adj beam and optical adj system and electrostatic adj detector	USPAT; EPO; JPO; DERWENT	2002/12/13 14:57
-	0	250/\$.ccls. and electron adj beam and optical adj system and duel adj magnetic adj pole	USPAT; EPO; JPO; DERWENT	2002/12/13 15:43
-	6	((("4806754") or ("5770863"))).PN.	USPAT; EPO; JPO; DERWENT	2002/12/13 16:13
-	21	scanning adj electron adj microscope and secondary adj electron and lens and shield and capacitor	USPAT; EPO; JPO; DERWENT	2003/04/22 15:38
-	48	scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5	USPAT; EPO; JPO; DERWENT	2003/04/22 14:24
-	39	(scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and 250/\$.ccls.	USPAT; EPO; JPO; DERWENT	2003/04/22 13:25
-	10	((scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and 250/\$.ccls.) and shield	USPAT; EPO; JPO; DERWENT	2003/04/22 13:27
-	0	((((scanning adj electron adj microscope and auger adj electron and deflect\$4 and analyz\$5) and 250/\$.ccls.) and shield) and gradient	USPAT; EPO; JPO; DERWENT	2003/04/22 13:27
-	13	scanning adj electron adj microscope and deflect\$4 and analyz\$5 and shield and gradient	USPAT; EPO; JPO; DERWENT	2003/04/22 13:28
-	108	scanning adj electron adj microscope and secondary adj electron and lens and shield	USPAT; EPO; JPO; DERWENT	2003/04/22 14:11
-	18	(scanning adj electron adj microscope and secondary adj electron and lens and shield) and auger	USPAT; EPO; JPO; DERWENT	2003/04/22 14:12
-	10	scanning adj electron adj microscope and auger adj electron and deflect\$4 and capacitor	USPAT; EPO; JPO; DERWENT	2003/04/22 16:38
-	680	scanning adj electron adj microscope and secondary adj electron and resolution	USPAT; EPO; JPO; DERWENT	2003/04/22 15:52
-	437	(scanning adj electron adj microscope and secondary adj electron and resolution) and 250/\$.ccls.	USPAT; EPO; JPO; DERWENT	2003/04/22 15:39
-	343	scanning adj electron adj microscope and secondary adj electron and resolution same beam and 250/\$.ccls.	USPAT; EPO; JPO; DERWENT	2003/04/22 15:53
-	247	scanning adj electron adj microscope and secondary adj electron and resolution with beam and 250/\$.ccls.	USPAT; EPO; JPO; DERWENT	2003/04/22 15:54
-	98	scanning adj electron adj microscope and auger adj electron and efficiency	USPAT; EPO; JPO; DERWENT	2003/04/22 16:38
-	9	scanning adj electron adj microscope and auger adj electron and collection adj efficiency	USPAT; EPO; JPO; DERWENT	2003/04/22 16:39

-	16	250/\$.ccls. and electron adj beam and lens and shield and conductive and resistive	USPAT; EPO; JPO; DERWENT	2003/04/23 08:18
-	151	250/\$.ccls. and electron adj beam and objective adj lens and shield	USPAT; EPO; JPO; DERWENT	2003/04/23 08:49
-	102	250/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector	USPAT; EPO; JPO; DERWENT	2003/04/23 08:26
-	23	250/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector not magnetic	USPAT; EPO; JPO; DERWENT	2003/04/23 08:27
-	10	(250/\$.ccls. and electron adj beam and objective adj lens and electrostatic adj deflector not magnetic) and secondary adj electron	USPAT; EPO; JPO; DERWENT	2003/04/23 08:27
-	20	250/\$.ccls. and electron adj beam and objective adj lens and deflector and auger adj electron	USPAT; EPO; JPO; DERWENT	2003/04/23 10:48
-	6	250/\$.ccls. and electron adj beam and lens and deflector and auger adj electron and capacitor	USPAT; EPO; JPO; DERWENT	2003/04/23 10:41
-	19	250/\$.ccls. and electron adj beam and objective adj lens and deflector and auger adj electron and image	USPAT; EPO; JPO; DERWENT	2003/04/23 10:48